IN THE CLAIMS

Please amend the claims as follows:

Claims 1-18 (Cancelled)

19. (Currently Amended) A stamper for embossing at least one pattern of recesses in a surface of a substrate for a magnetic recording medium, said substrate surface including spaced-apart landing and data zones, said stamper comprising:

(a) a main body including a surface; and

(b) ~~means~~ a first patterning unit for embossing a pattern of sinusoidally-shaped recesses in said landing zone of said substrate surface,

wherein the surface of the main body is Al/NiP.

20. (Currently Amended) The stamper as in claim 19, further comprising:

(c) ~~means~~ a second patterning unit for simultaneously embossing a servo pattern in said data zone of said substrate surface.

21. (Currently Amended) A stamper for embossing at least one pattern of recesses in a surface of a substrate for a magnetic recording medium, the stamper comprising:

a stamping surface including a pattern of sinusoidally-shaped protrusions,

wherein said pattern of sinusoidally-shaped protrusions is a negative image of the pattern of recesses to be embossed in the surface of the substrate, and

said stamping surface is Al/NiP.

22-24. (Cancelled)

25. (Currently amended - Withdrawn) The stamper according to claim 21, wherein said stamping surface further comprises a hydrophobic polymer.

26. (Previously Presented) The stamper according to claim 21, wherein said pattern of sinusoidally-shaped protrusions comprises a plurality of spaced apart peaks and valleys, wherein a peak-to-peak spacing of adjacent peaks is in the range from about 0.1 to about 10 μm and a depth of each valley is in the range from about 10 to about 200 Å.